

Journal Pre-proofs

Short communication

Characterization of jet nebulizer spray pyrolysis coated MoS₂ thin films and fabrication of p-Si/n-MoS₂ junction diodes for optoelectronic application

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PII: S1387-7003(21)00256-2
DOI: <https://doi.org/10.1016/j.inoche.2021.108701>
Reference: INOCHE 108701

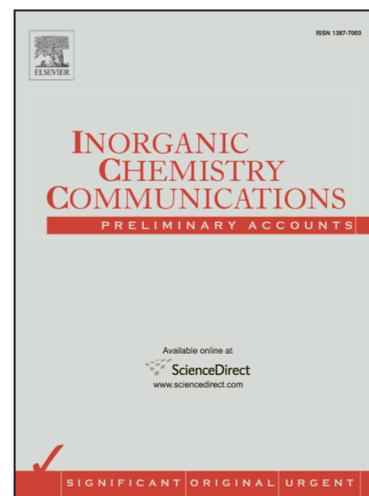
To appear in: *Inorganic Chemistry Communications*

Received Date: 19 March 2021
Revised Date: 24 May 2021
Accepted Date: 29 May 2021

Please cite this article as: T. Sasikala, K. Shanmugasundaram, P. Thirunavukkarasu, J. Chandrasekaran, P. Vivek, R. Marnadu, M. Aslam Manthrammel, S. Gunasekaran, Characterization of jet nebulizer spray pyrolysis coated MoS₂ thin films and fabrication of p-Si/n-MoS₂ junction diodes for optoelectronic application, *Inorganic Chemistry Communications* (2021), doi: <https://doi.org/10.1016/j.inoche.2021.108701>

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Characterization of jet nebulizer spray pyrolysis coated MoS₂ thin films and fabrication of p-Si/n-MoS₂ junction diodes for optoelectronic application

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Graphical abstract

Highlights

A nanostructured MoS₂ thin films were prepared on glass substrate by JNSP technique.

The elongated irregular rod-like structures were revealed through FESEM

The MoS₂ films deposited at 450°C exhibit minimum band gap.

We have fabricated p-Si/n-MoS₂ junction diode for different substrate temperature

A minimum ideality factor of 2.23 was obtained for 550 °C

Abstract

Inorganic two-dimensional materials are gradually becoming resources for modern electronic device manufacturing. Fascinate of 2D transition metal dicholgonides (TMDs) are particularly high. TMDS are very great potential for their characteristics and band gap structure in optoelectronic devices. In TMDs, 2D MoS₂ is most researchable material due to its good performance and its adequacy of electronic and optoelectronic application. Here we demonstrate MoS₂ thin film for various temperature such as 400, 450, 500, 550°C via Jet

Nebulizer Spray Pyrolysis (JNSP) technique for PN diode application. XRD pattern revealed that the polycrystalline nature of MoS₂ films with hexagonal crystal structure. The elongated irregular rod-like structures were revealed through FESEM. Elemental confirmation studies of Mo and S were done through EDX. The MoS₂ films deposited at 550°C exhibit minimum band gap. The average conductivity values were found to be increased from 1.730×10^{-8} to 3.877×10^{-7} S/cm with substrate temperature. A positive photo conducting-nature of p-Si/n-MoS₂ diode have been fabricated. Remarkably, the p-Si/n-MoS₂ diode fabricated at 550 °C revealed minimum n values of 2.23.

Keywords: MoS₂ thin films; P-N junction diode; spray pyrolysis; I-V characterization

1. Introduction

Recently, two dimensional (2D) layered transition metal dichalcogenide (TMD) materials like disulphides and diselenides of Molybdenum (MoS₂ and MoSe₂) and Tungsten (WS₂ and WSe₂), Zirconium Disulfide (ZrS₂) and Rhenium disulphide (ReS₂) [1-6] are transpiring as exciting peer group materials for production of thin electronics devices. Among these TMD materials, a MoS₂ thin film in particular has gained significant interest with research community due to its remarkable optical, electrical and optoelectronic properties. The bulk MoS₂ in general have reported an indirect transition nature with the energy gap of 1.2 eV and its direct energy gap is around 1.8eV [7]. It has carrier mobility 1-40 (cm²/Vs) [8], higher optical absorption [9], high current switching ratio ($\sim 10^8$) [10] and a strong excitonic binding energy [11] and fast photo-response [12]. In the last decade, various MoS₂ thin films were developed in order to improve their optoelectronic properties [13-17]. Sungjin Wi et al., [18] have fabricated plasma-assisted p-n junctions in multilayer MoS₂ photovoltaic (PV) devices which results good power, high photocurrent up to 20.9 mA/cm² and high external quantum efficiencies. Yuka Tsuboi et al., [19] demonstrated photovoltaic performances of solar cells were significantly archived higher PV efficiency of 11.1%. Meng-Lin Tsai et al., [20] reported the peak power conversion efficiency for PV cells based on monolayer TMD, where they observed 5.23% efficiency. Chung-Che Huang et al., [21] reported that nano-scale MoS₂ thin films were promising materials for optoelectronic applications. These authors found that the substrate material and annealing temperature plays a remarkable role in formation of single crystalline structure in MoS₂ thin films. In this context, C. Jiang et al., [22] developed transistors for high temperature application using MoS₂ thin films their operating temperature range upon 500K. Juhong Park et al., [10] reported optical and electrical parameters form their studies the optical transparency more than 90%, electrical mobility of ~ 12.24 cm²V⁻¹ s⁻¹ and I_{on/off} ratio of $\sim 10^6$ obtained in prepared MoS₂ thin films

and authors claimed these films flexible electronic applications compared with organic films. Yijin Zhang et al., [23] demonstrated that a thin transistor made of p-type MoS₂ achieved a high switching ratio for FET operations, and high hole mobility ($\mu_{\text{max}} \sim 86 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$), which is double of electron mobility. Meanwhile, in the recent year's researchers have developed MoS₂ thin films for various application including photodetectors [24,25], gates [26], transistors [27], flexible biosensors [28] and light emitting diodes [29]. Until now, various methods have been adopted such as chemical vapour deposition [30], sputtering [31], atmospheric-pressure hydrogen reduction [32], chemical bath deposition method [33], sol-gel [34], solar cell [35], plasma evaporation [36] and spray pyrolysis. Ju Hyeong Kim et al., [37] have reported MoS₂ film by spray pyrolysis method. Until now, no articles have reported about preparation of Molybdenum disulphide (MoS₂) thin film using particular JNSP techniques. The JNSP technique has many advantage and is widely adopted in laboratories because of its simple handling method, low cost, better surface uniformity, extensive choice of precursors ability to control particle shape and size, composition and phase homogeneity of the film, capacity to produce large area high quality films of uniform thickness, the addition of dopants to the spray solution is simple, it is easy to prepare films of any composition by simply mixing the components in the appropriate ratios [38].

In this work, we have developed MoS₂ thin films with various substrate temperatures, 400, 450, 500 and 550 °C via JNSP techniques. Since it has several benefits like cost-effective, simple experimental setup, uniform coating, less operating temperature and small amount of precursor solution enough to get purity in films. Moreover, the prepared films were characterized by XRD, RAMAN, FESEM, UV-vis spectrometer and I-V characteristics for investigate the structural, optical and electrical properties of these MoS₂ thin films. Further, we have fabricated MoS₂ thin film based hetrojunction diodes. Here in there are many diode parameters were explored including saturation current (I_0), ideality factor (n), barrier height (Φ), for various substrate temperatures.

2 Experimental procedure

2.1 Materials

An Aqueous solution or uncongealed solution of Molybdenum Disulphide (MoS₂), (99.8%), glass substrates, 1×1cm p- silicon wafers, hydrochloric acid and isopropanol are procured from SIGMA Aldrich. The nebulizer kit was purchased from medical shop.

2.2. Preparation of MoS₂ thin films

Nanostructured MoS₂ films were coated using various substrate temperature through JNSP technique using the RT mixed solution prepared by dissolving 0.05M of MoS₂ in HCL with continuous stirrer for 30 min. The spray pyrolysis has been employed on the thoroughly cleaned glass substrates (2 cm x 2.5 cm) at various substrate temperature; viz. 400, 450, 500 and 550 °C. The spray nozzle - substrate distance was kept at 5 cm. Pure MoS₂ Nano plate films were successfully grown as material droplets undergoing thermal decomposition at different substrate temperatures. The complete experimental setup of JNSP technique is shown in Fig. 1.

2.3 Assembly of p-Si/n-MoS₂ diodes

MoS₂ Nano plate /p-Si diodes are grown on 1 cm× 1 cm p-Si substrate. Initially, the undesired surface oxide layer and impurities were removed by dipping the p-Si in 3:1 sulfuric acid - hydrogen peroxide mixture for 1.0 min. They are further cleaned with diluted HCL and then double distilled water. MoS₂ Nano films are coated on the p-Si, placed at different temperatures of 400, 450, 500 and 550°C. The contacts are extended on both sides of the prepared MoS₂/p-Si diode using silver paste blended with isoamyl acetate. The schematic diagram of fabricated p-Si/n-MoS₂ diode is shown in Fig. 2

2.4 Characterization

The structural analyses of the samples were carried out using a Rigaku Ultima III XRD with Cu K α radiation of continuous scanning with PSD mode. RAMAN Spectra was analyzed by confocal raman spectra(WiTec Alpha 300, Germany). The morphological studies were done using a RA-ZEI-001 model FESEM (Code R14401, CARL ZEISS) equipped with EDAX setup (QUANTAX 200, CODE 1103-0000:400, BRUKER). A JASCO UV-Vis spectroscope was used to study optical properties of the prepared samples, in the range 200 - 900 nm. A Keithley 6517-B electrometer and a PEC-L01S solar simulator were used to carry out the electrical properties of the MoS₂ diodes.

3 Results and discussion

3.1 XRD analysis

Fig. 3 displays XRD patterns of MoS₂ thin films grown at 400, 450, 500 and 550°C respectively. The peaks for all the films prepared at different temperatures are found matching well with the JCPDS No 037-1492 which conforming hexagonal crystal structure of MoS₂ films with. From XRD pattern, it is very evident that the grown films are preferentially oriented towards (002) at 400-550°C. The XRD also displays emergence or growth of new peaks with temperature. For example, the (103) peak for the film grown at 400°C and (021)

peak for the film grown at 450°C are emerged with considerably high intensity compared to the films grown at 400°C. However, the film grown at 550°C doesn't show any particular preferential orientation and the intensity of (021) peak has reached above (002) peak. The (021) peak is related to MoO₃ which are found to be started to grown after 400 °C indicating the secondary phase (Orthorhombic) due to the oxidization during deposition at higher temperature. This result clearly indicates that the substrate temperature is strongly influences the MoS₂ thin films. The (021) peak matched with JCPDS file No. 05-508 [39]. However, all other peaks are related to MoS₂ films (Hexagonal). It was also noted that the FWHM (β) for the peaks are increasing with the growth temperature and could be attributed to the increasing crystallite sizes with the temperature. Scherer formula was employed to estimate the crystallite sizes of the thin films, and the growing crystallite sizes (D) with the deposition temperature were confirmed. Also, microstrain (ϵ) values, dislocation density (δ) and stacking fault probability (SF) values were estimated using the relations,

$$\epsilon = \beta \cot(\theta)/4 \quad (1)$$

$$\delta = 1/D^2 \quad (2)$$

$$SF = [2\pi^2/(45\sqrt{3}\tan(\theta))]\Delta(2\theta) \quad (3)$$

where $\Delta(2\theta)$ is the observed shift in the 2θ positions. The obtained results are tabulated in **Table 1**. The ϵ , δ and SF values are found decreasing with the deposition temperature. Similar observations have been observed for the CdSe thin films prepared by thermal evaporation. The decreasing tendency of number of dislocations per unit area and stacking fault could be due to the increasing crystallite sizes with temperature and rearrangements happening with the increasing temperature. The stacking fault was calculated based on all the peaks observed from XRD. The stacking fault is referred to the deviation in the stacking sequence of the hexagonal wurtzite structure. So, the decrease in SF could mean a better stacking sequence in the structure.

3.2 Raman analysis

The Raman spectra for MoS₂ thin films prepared at different temperature as 400°C, 450, 500, 550 °C are shown in figure 4 (a-d). A small shoulder peak observed at 286 cm⁻¹ are corresponding to the E_{1g} mode of vibration due to the S-Mo-S layer of atoms where the intensity of this particular peak increased when increasing the annealing temperature [40]. In figure 4 (a-d) two distinct peaks present in 384, 406 cm⁻¹ which clearly confirms the MoS₂

phase in the sample. The intense less turn out at 384 cm^{-1} is attributed to E_{2g}^1 phonon mode because of in-plane of vibration mode where the mode is terrace terminated vibration of opposite direction on sulfur atom and molybdenum atom [41-42]. A characteristic peak at 406 cm^{-1} is corresponding to A_{1g} out-plane vibrational mode of sulfur atom in the direction perpendicular to the plane [43]. Comparing the intensity difference between the two major activation modes of peaks the vertical plane of A_{1g} is much intense the E_{2g}^1 that may be attributes to the polarization dependence of edge-terminated structure of MoS_2 [44-46]. The frequency difference between these two peaks was $\sim 22\text{ cm}^{-1}$ which may be due to the monolayer behaviour of the MoS_2 [47]. A broad shoulder peak observed at 454 cm^{-1} is represents the longitudinal acoustic mode of vibration [48]. The sharp peak appeared in 820 cm^{-1} corresponding the mode of $2A_{1g}$ mode of vibration which is a second order mode peak due to the thermal effect on the sample this peak related to MoO_3 [49]. Interestingly we can note that some additional weakly contributed peaks in the frequency range of 80 to 250 cm^{-1} appeared for the film prepared at 500°C which may be the structural change due to the change of temperature.

3.3 FESEM and EDX

Surface morphologies of the MoS_2 thin films prepared at 400 , 450 , 500 and 550°C deposition temperatures are depicted in FESEM images, in **Fig. 5(a-d)**. From **Fig. 5**, the grains are formed as the elongated irregular rod structures. However, with the temperatures, the grain sizes are increasing and becoming more closely packed. The films grown at 550°C show an apparent unidirectional growth of majority of the grains. The micrographs also show dense layered structure of MoS_2 films, and thus might be exhibiting an indirect bandgap nature. the EDAX spectrum of the MoS_2 thin films with different deposition temperatures is shown in **Fig. 6**. From EDX spectrum, the important elements like Mo, S and O have been confirmed on the coated MoS_2 films. The obtained atomic ratio (%) of Mo is 13.48, 16.59, 12.18 and 9.54 for 400 , 450 , 500 , 550°C . Similarly, atomic ratio (%) of O and S are 61.56, 37.43, 58.46, 62.76 and 11.23, 10.09, 2.58, 1.50 for 400 , 450 , 500 , 550°C . Other impurities like C, Na, Ca, Si was also observed due to the glass substrates. At higher substrate temperature, the atomic ratio (%) of Mo and S decreased and the O % increased. The substrate temperature strongly influences the composition of the MoS_2 films.

3.4 UV-Vis

Fig. 7 a & b represents optical absorption and transmission spectra of MoS₂ films prepared at various deposition temperatures. The absorption spectra show strong absorption region below 350 nm. The transmission spectra also validate this observation. The maximum transmission of ~50% is observed for the pure MoS₂ film, which was found systematically decline with the deposition temperature. The reason for this lowering of transmission could be attributed to the increasing crystallite size with the increasing deposition temperature. Also, red shifts in the absorption edges can be seen from these spectra with the increasing growth temperature, and could be attributed to the increasing crystallite sizes. The absorption coefficients, α were calculated from the transmittance (T) using the following relation,

$$\alpha = \frac{2.303 \times \log\left(\frac{1}{T}\right)}{t} \quad (4)$$

Where T is the transmittance and t is the thickness of the MoS₂ films.

The band gap relation of the MoS₂ films can be obtained using the relationship

$$(\alpha h\nu)^2 = A(h\nu - E_g) \quad (5)$$

Where $h\nu$ is the incidence photon energy, E_g is the band gap energy and A is a constant. The value of E_g were estimated from the linear extrapolations of $(\alpha h\nu)^2$ vs. $h\nu$ plots, on $h\nu$ axis. From the plots, it was very much evident that the band gap values were systematically decreasing with the deposition temperature. The bulk MoS₂ is an indirect bandgap ($E_g=1.29$ eV) semiconductor with multilayers, whereas monolayer MoS₂ is a direct bandgap material, with $E_g=1.9$ eV [50-53]. From the **Fig. 7c**, the direct band estimations are almost in the same range, and are higher than the reported value for bulk samples. The reason could be attributed to the highly nanostructured growth of the prepared MoS₂ samples [53]. The observed red shift or the reducing tendency of the band gap with the growth temperature is due the increasing crystallite size with the temperature. The thicknesses of the films were estimated to be around 400 nm, and it could be inferred that the band gap energies of prepared films are of indirect in nature. Moreover, the variations of optical parameters with temperature are presented in **Fig. 7d**. Both absorption and extinction coefficient are increased linearly with temperature.

3.5 Electrical conductivity

The electrical behaviour of the spray coated MoS₂ thin films were studied through a facile two-point probe setup. The change of current values with temperature were recorded by applying a positive voltage ranging from 0 to 100 (step of 20) as shown in **Fig. 8a**. It is noted from the **Fig. 8a** that the current values are strongly dependant with temperature. The higher

temperature showed a huge difference in current values when compared to lower temperature. The formation of oxygen vacancy can influence the electrical characteristics of the samples. The resistivity of the films was determined from the I-V characteristics by the following equation.

$$\rho = R\left(\frac{A}{t}\right)\Omega\text{cm} \quad (6)$$

Numerous literatures advocate that the electrical resistivity of the thin film depends on the crystallizations of the prepared film, type of surface structure, deposition technique and preparative parameters, etc. The resistivity of the present MoS₂ films is favorably reduced as 7.29 ×10⁷, 4.33×10⁷, 7.77×10⁶, 5.99×10⁶ Ω cm for 400, 450, 500, 500 °C. Decrease in resistivity with increasing temperature is accredited to the creation of more oxygen vacancy during the film deposition and increase in crystallite size of the MoS₂ films [54]. The conductivity of the samples was assessed by the relation and listed in Table 2.

$$\sigma_{\text{dc}} = \frac{t}{RA} \quad (7)$$

The Arrhenius plot (**Fig.8b**) showed that the large variation in the electrical conductivity with inverse temperature and also specifies the existence of double conduction mechanisms (CM). For high-temperature part is related to the grain boundary scattering limited CM and low-temperature part is related to variable range hopping CM [55]. The substrate temperatures effectively improve the electrical conductivity particularly 550 °C as shown in **Fig.8c**. The calculated average conductivity values were found to be increased from 1.730×10⁻⁸ to 3.877×10⁻⁷ S/cm with substrate temperature. The obtained conductivity values are suggesting the semiconducting nature of the MoS₂ films. The conductivity maximum of 3.877×10⁻⁷ S/cm was observed at higher crystallite size of MoS₂ film. We observed that the MoS₂ film with higher crystallite size can facilitate to enhance the conductivity of the films. The decrease in the grain-boundary scattering also aids to enhances the film conductivity [56]. The activation energy (E_a) of the MoS₂ films was determined from the slop of Arrhenius plot. The E_a was found to decreased from 0.129 to 0.038 eV with substrate temperature. The variation in E_a is mostly due to the expansion in crystallinity, thickness of the film and lesser defect concentration.

3.6 I-V characteristics of p-Si/n-MoS₂ junction diodes

The forward and reverse characteristics of the fabricated p-Si/n-MoS₂ junction diode are shown in **Fig. 9a**. To understand the photo-response of the present diode, we have

measured both dark and photocurrent of the diode by applying bias voltage -4 to +4 V. For photocurrent measurement, the intensity of the light was fixed as 100 mW/cm². The wavelength range of the solar simulator is ~ 400-1100 nm (as per JIS C 8912 standard). The irradiance comes through an air mass 1.5 G filter and fall on the diode. The thickness of the emitter layer is around 500-600 nm. From the p-Si/n-MoS₂ diode curve, it is clear that all the diode showed positive photo-response at 100 mW/cm² relatively under dark condition. Moreover, the obtained superior forward current and weaker reverse current implying the photo-conducting properties of the fabricated diode. The current transport mechanism of p-Si/n-MoS₂ is studied and described by traditional thermionic emission (TE) principle as follows [57-59].

$$I = I_0 \left[\exp\left(\frac{qV}{n k_B T} - 1\right) \right] \quad (8)$$

where I_0 , q , V , n , k_B and T are the reverse saturation current, charge of electron, applied potential, ideality factor, Boltzmann constant and temperature. The ideality factor (n) and barrier height (Φ_B) are the key parameters to understand the device performance. The n and Φ_B of the p-Si/n-MoS₂ diodes were determined from semi-logarithmic plot (**Fig. 9b**) through the following equations [57,58].

$$n = \frac{q}{k_B T} \left(\frac{d}{d(\ln(J))} (V) \right) \quad (9)$$

$$\Phi_B = \frac{k_B T}{q} \ln \left(\frac{A^* A T^2}{J_0} \right) \quad (10)$$

Here, $A^* = 32 \text{ A/cm}^2 \text{ K}^{-2}$, the effective Richardson constant for p-Si.

The estimated n and Φ_B values were compared in Table 3. The estimated n and Φ_B values are very sensitive with substrate temperature, especially at higher. The p-Si/n-MoS₂ diodes showed a favourable trending of increasing ideality factor with reducing barrier height while decreasing substrate temperature from 550 to 400 °C. Many literatures have been reported a similar behaviour in various junction diodes [57-63]. At lower temperature, the electron doesn't have enough energy to pass the barrier potential. But, at higher temperature, electron gains adequate energy to cross this barrier. Hence, our diode revealed better diode performance at higher temperature. Besides, all the diodes recorded higher photocurrent under light exposed condition i.e 100 mW/cm² which is attributed to due to the formation of superior photo-carrier charge cupules with lessor recombination. Remarkably, the p-Si/n-

MoS₂ diode fabricated at 550 °C revealed minimum n values of 2.23. The 400 and 450 °C showed higher n values due to the weak temperature, lesser separation of charge cupules, image force lowering, tunnelling. Also, the native oxide layer SiO₂ will be formed during deposition which may also affect the ideality factor of the diode. Moreover, the Φ_B values varied from 0.541 to 0.729 eV with temperature. The excremental Φ_B is mostly influenced by the diffusion of minority charge carriers between n-side and p-side and thickness of the depletion region.

4. Conclusion

A nanostructured MoS₂ thin films and p-Si/n-MoS₂ diodes were successfully grown at different substrate temperatures using JNSP method. The impacts of growth temperature on various features including structural and electrical characteristics of MoS₂ thin films were studied. The XRD patterns confirm the hexagonal and Orthorhombic phase of the MoS₂/MoO₃ thin films temperature between 400 to 550 °C. The average crystallite size of MoS₂ thin film changed from 31.16 to 45.50 nm. From FESEM results, the films grown at 550°C show an apparent unidirectional growth of majority of the grains. The maximum absorption and the band gap minimum (of 2.6 eV) were observed for the film deposited at 550°C. From I-V characteristics, the resistivity of MoS₂ was favorably reduced while increasing substrate temperature. The n-MoS₂/p-Si junction diode recorded lower n value under light conations, exhibiting the photo detection nature of the diode. This photo response behavior makes these diodes suitable for photo detector applications.

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Fig. 1. Schematic diagram of jet nebulizer spray pyrolysis setup

Fig. 2. Schematic diagram of $\text{p-Si}/\text{n-MoS}_2$ junction diode

Fig. 3. XRD patterns of MoS_2 thin films prepared at 400, 450, 500 and 550 °C with JCPDS.

Fig. 4. Raman spectra for MoS_2 thin film coated at different temperature.

Fig. 5. SEM images of the MoS₂ thin films prepared at different deposition temperatures

Fig. 6. EDX spectrum of the MoS₂ thin films

Fig. 7. a) Optical absorption, b) transmission and c) Tauc's plot for indirect and d) variations of optical parameters of MoS₂ thin films prepared at different deposition temperatures

Fig. 8. (a) I-V characteristics of MoS₂ films for different substrate temperature (b) Arrhenius plot (c) Variation of activation energy and conductivity with substrate temperature

Fig. 9. (a) I-V characteristics (b) semi-logarithmic plot of p-Si/n-MoS₂ diode for different substrate temperature

Table 1. Structural parameter of MoS₂ thin films for various temperature

| Substrate Temperature (°C) | Crystalline Size D (nm) | Micro strain (ε) | Dislocation density (δ) × 10 ⁻¹⁴ (lines cm ⁻²) | Stacking fault (SF) × 10 ⁻² |
|----------------------------|-------------------------|------------------|---|--|
| 400 | 31.16 | 0.0176 | 4.605 | 0.5402 |
| 450 | 35.68 | 0.0139 | 2.564 | 0.4481 |
| 500 | 37.37 | 0.0126 | 2.071 | 0.3215 |
| 550 | 45.02 | 0.0090 | 1.915 | 0.2546 |

Table 2. Electrical parameters of MoS₂ films for different substrate temperature

| Substrate temperature (°C) | Average Resistivity (ρ) (Ω cm) | Average conductivity (S/cm) | Average activation energy (E_a) (eV) |
|-----------------------------------|---|------------------------------------|--|
| 400 | 7.29×10^7 | 1.730×10^{-8} | 0.129 |
| 450 | 4.33×10^7 | 3.578×10^{-8} | 0.083 |
| 500 | 7.77×10^6 | 1.228×10^{-7} | 0.064 |
| 550 | 5.99×10^6 | 3.877×10^{-7} | 0.038 |

Table 3. p-Si/n-MoS₂ diode parameters for different substrate temperature

| Substrate temperature (°C) | Barrier height (Φ) | | Ideality factor (n) | |
|-----------------------------------|---|--------------|----------------------------|--------------|
| | Dark | Light | Dark | Light |
| 400 | 0.55 | 0.54 | 5.80 | 4.40 |
| 450 | 0.60 | 0.62 | 4.57 | 3.32 |
| 500 | 0.62 | 0.66 | 4.51 | 2.69 |
| 550 | 0.68 | 0.72 | 3.23 | 2.23 |